

Chamber Oven

(High temperature sintering with temperature profiling)

Manufacturer: Nabertherm

Model: HTCT 03/16



General Description:

The High Temperature Chamber Oven is designed for thermal processing of small to medium large samples up to 1600 °C. The chamber can achieve fast heating rates (up to 30 °C/min) and allows working under controllable atmosphere using an automatic gas-flow controller.

Key Specifications:

- Maximal T: 1600 °C
- Heating elements: SiC
- Chamber dimensions: 120 x 210 x 120 mm
- Maximal heating range: 30 °C/min
- Controlled atmosphere: automatic gassing system; calibration for N₂
- Digital PID-temperature control

Availability:

Use allowed for all researchers with permission

Location

Environmental Lab
 Europastraße 12
 9524 Villach

Responsibles / Contact

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